

# Development of an Smart Tool Holder for Online Error Monitoring in Single Point Diamond Turning

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*The increasing demands for optical functional surfaces with complex micro-structures and high form precision push up the accuracy requirements of SPDT(Single Point Diamond Turning). Online error monitoring ensures the continuity of the machining process, enabling efficient evaluation of machining quality and timely correction of machine tool drift errors, thereby playing an increasingly important role in manufacturing. However, the relatively harsh environment during the SPDT process, such as the blockage of chips, the extremely small processing area, severely limit the detection accuracy of conventional sensors like optical lenses and probes. In this work, a high-sensitivity, high-stiffness smart tool holder for three-axis cutting force measurement is developed based on a flexible hinge mechanism with symmetrically distributed piezoelectric sensors. A high-precision, low-cost detection solution for picoCoulomb-level weak charges is provided, achieving online detection of cutting forces with a resolution of 1mN. Based on the smart tool holder, the mapping relationship between cutting force and the machined microstructure morphology is studied, and real-time online error monitoring in SPDT microstructure machining is achieved. Experiments conducted on polymethyl methacrylate have confirmed the stability and accuracy of the online error monitoring smart tool holder, with measurement deviations less than 1.7% compared to advanced offline detection methods. This method is of significant importance for achieving continuous high-consistency machining of large-area microstructured functional surfaces.*

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